IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

Applicant: Eiji Nishibe et al.

Serial No.: to be determined

Art Unit: Unknown

Examiner: Unknown

Filed : August 31, 2001

Title : SEMICONDUCTOR DEVICE AND MANUFACTURING METHOD THEREOF

Commissioner for Patents Washington, D.C. 20231

PRELIMINARY AMENDMENT

Prior to examination, please amend the application as follows:

In the abstract:

Insert the abstract after the last line on page 33.

-- A semiconductor device is provided with a gate electrode formed over a substrate that has gate oxide films disposed thereon. Source-drain regions of low and high concentration are formed next to the gate electrode. A diffusion region width of the source side of the source-drain regions is smaller than at least a diffusion region width of the drain side.--

CERTIFICATE OF MAILING BY EXPRESS MAIL

I hereby certify under 37 CFR §1.10 that this correspondence is being deposited with the United States Postal Service as Express Mail Post Office to Addressee with sufficient postage on the date indicated below and is addressed to the Commissioner for Patents, Washington,

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Attorney's Docket No.: 10417-093001 / F51/137275M/NS

REMARKS

An abstract is added based on the description of the present application. No new matter has been added.

Please apply any charges, if found necessary, or credits to Deposit Account No. 06-1050.

Respectfully submitted,

Date: 8/31/01

Chris T. Mizumote

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